ABSTRACT OF THE DISCLOSURE

A cleaning solution for semiconductor substrates comprising a nonionic surface active agent of the formula (1) and/or the formula (2), a chelating agent and a chelating accelerator:

$$CH_3 - (CH_2)_1 - O - (C_m H_{2m} O)_n - X$$
 (1)

wherein 1, m and n independently represent a positive number, and X represents a hydrogen atom or a hydrocarbon group;

$$CH_3 - (CH_2)_a - O - (C_bH_{2b}O)_d - (C_xH_{2x}O)_v - X$$
 (2)

wherein a, b, d, x and y independently represent a positive number, b and x are different, and X represents a hydrogen atom or a hydrocarbon group.